

METHOD FOR MANUFACTURING AND CONTROLLING
STRUCTURES AND PATTERNS OF SOLUBLE AND COLLOIDAL
SUBSTANCES BY PRINTING ON THE MICROMETER AND
NANOMETER SCALE AND WITH REDUCTION OF THE
5 DIMENSIONS OF THE STAMP'S FEATURES

ABSTRACT OF THE DISCLOSURE

10 A printing process for obtaining patterns of nanometer and
micrometer dimensions on a substrate, comprising i) the application of a
solution or suspension of an imprinting material to the substrate, ii) the
positioning, without applying pressure, of a stamp provided with relief
patterns at a distance of 0 nm to 500 μm from the substrate, and iii) the
15 evaporation of the solution or suspension.

(Figure 1)